

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Sakae KOYATA et al.

Group Art Unit : 1792

Appl. No. : 10/561,821

Examiner : OLSEN, Allan W.

Filed : February 7, 2007

Confirmation No. : 2851

For : PROCESSING METHOD OF SILICON WAFER

**AMENDMENT**

Commissioner for Patents  
U.S. Patent and Trademark Office  
Customer Service Window, Mail Stop Amendment  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314

Sir :

In response to the Office Action of May 28, 2009, please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims beginning on page 2.

**Remarks** begin on page 5.